

# 氧化銦錫透明導電層於磷化鋁鎵銦發光二極體的應用

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## 摘要

氧化銦錫(Indium-Tin Oxide, ITO)對可見光具高度透明度及電傳導性，常當做一個透明電極，被廣泛地使用在發光元件上。在傳統磷化鋁鎵銦(AIGaInP)材料的發光二極體上(Light-Emitting Diode, LED)，會有ITO與磷化鎵窗戶層(GaP window layer)難以形成良好歐姆接觸的問題，為解決這個問題，本研究使用Ni/ITO層來與GaP形成良好的歐姆接觸。本研究使用電子束蒸鍍系統在載玻片上面分別蒸鍍ITO(230 nm)與Ni(6 nm)/ITO(230 nm)，進行穿透率和片電阻的量測，接著鍍在AIGaInP的LED上，與GaP和GaP/ITO結構的LED進行I-V和L-I的光電特性分析。在本實驗中光波長630 nm下Ni/ITO薄膜穿透率可達91%。Ni/ITO膜在450 空氣環境中以爐管退火15分鐘，得到最低的片電阻值，應用在AIGaInP LEDs當作window layer的接觸層，在20 mA驅動電流下，GaP/Ni/ITO結構的LED操作電壓分別比GaP和GaP/ITO結構LED降低0.04 V和0.13 V。在100 mA的驅動電流下，GaP/Ni/ITO結構的LED分別比GaP和GaP/ITO結構LED的亮度增加23%和61.5%。

關鍵詞：氧化銦錫、磷化鋁鎵銦、發光二極體

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